

In the Claims

Please amend Claims 1, 7, and 19 as indicated in the VERSION WITH MARKINGS TO SHOW CHANGES MADE to read as shown below.

Sub C1
1. (Twice Amended) A method of using a recording device that records a pressure in a vacuum device that is not a silicon wafer processing device, the vacuum device enabled to couple to a fetus, comprising:
detecting a pressure in the vacuum device, the vacuum device enabled to couple to a fetus;
recording the pressure in the vacuum device; and
storing a record of the pressure.

Sub C2
7. (Twice Amended) A method of using a recording device to record a pressure in a vacuum device that is not a silicon wafer processing device, the vacuum device enabled to couple to a fetus, comprising:
placing the vacuum device on a fetus, the space between the fetus and the vacuum device having a pressure;
initiating a vacuum pressure in the suction device;
detecting the vacuum pressure in the suction device; and
automatically recording the vacuum pressure in the suction device.

Sub C3
19. (Twice Amended) A method of using a recording device to record a pressure in a vacuum device that is not a silicon wafer processing device, the vacuum device enabled to couple to a fetus, comprising:
coupling the recording device to the vacuum device, the vacuum device enabled to couple to a fetus; and
recording the pressure so that a record may be produced therefrom.